





Foreword

The papers in this special issue were presented at the ECI Conference on Solid-Liquid Separation Systems IV, which was held at the Gran Hotel Pucón Resort & Club, Pucón, Chile in 14-19 December 2003. Authors were invited to submit their papers, which were peer-reviewed before publication in this issue.

Following procedures of the previous meeting in Davos, Switzerland in 2001, the conference was organized in five sessions: (1) fundamentals of particulate systems in solid-liquid separation; (2) laboratory studies for parameter determination; (3) physico-mathematical modeling and simulation of solid-liquid separation processes; (4) solid-liquid separation equipment; and (5) solid-liquid separation processes.

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Participants had the opportunity to visit the beautiful small town of Pucón with their many attractions, especially the excursion into the Villarrica volcano.

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